Attorney Docket No. S-6099 PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of Dmitry Znamesky et al.

Serial No.: 10/733,761 Examiner: Not Yet Assigned

Filed: December 12, 2003 Art Unit: Not Yet Assigned

For: Micro Electromechanical Systems for Delivering High Purity Fluids in a Chemical Delivery System

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Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

INFORMATION DISCLOSURE STATEMENT TRANSMITTAL

Enclosed is an Information Disclosure Statement and accompanying Form PTO/SB/08A for the above-identified patent application.

☒ In accordance with 37 C.F.R. §1.97(b), no additional fee for submission of the IDS is required.

☐ In accordance with 37 C.F.R. §1.97(c), also enclosed is:

- ☐ the fee of $180.00 as set forth in 37 C.F.R. §1.17(p); or
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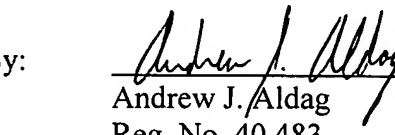
Dated: February 24, 2004

Respectfully submitted by
EDELL, SHAPIRO & FINNAN, LLC

By: 
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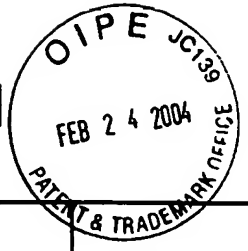

PTO/SB/08A (08-00)

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 1 of 3

Complete if Known	
Application Number	10/733,761
Filing Date	December 12, 2003
First Named Inventor	Dmitry Znamesky et al.
Group Art Unit	
Examiner Name	
Attorney Docket Number	S-6099

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.[1]	U.S. Patent Document Number	Kind Code[2] (*if known*)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
		4,821,997		Zdeblick	04/18/89
		5,069,419		Jerman	12/03/91
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		6,592,098	B2	Kao et al.	07/15/03

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No.[1]	Foreign Patent Document Office[3]	Number[4]	Kind Code[5] (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	T[6]

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[2] See attached Kinds of U.S. Patent Documents.
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[4] For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.
[5] Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible.
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Substitute for form 1449B/PTO **INFORMATION DISCLOSURE STATEMENT BY APPLICANT** *(use as many sheets as necessary)*				***Complete if Known***	
				Application Number	10/733,761
				Filing Date	December 12, 2003
				First Named Inventor	Dmitry Znamesky et al.
				Group Art Unit	
				Examiner Name	
Sheet	2	of	3	Attorney Docket Number	S-6099

OTHER DOCUMENTS – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.[1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T[2]
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Sheet	3	of	3	Attorney Docket Number	S-6099

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		J.M. GIRARD, et al., Contamination - free delivery of advanced precursors for new materials introduction in IC manufacturing, Future FAB International Issue 13 - Contamination Control , pp. 157-162, July 2002.	
		PATRICK COOLEY, et al., Applications of Ink-Jet Printing Technology to BioMEMS and Microfluidic Systems, Microfluidics and Biomems, Proceedings of SPIEVA, 4560 (2001), pp. 177-188.	
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		ALBERT K. HENNING, et al., Evaluating the use of MEMS-based gas and fluid delivery systems, MICRO, July/August 1998, 7 pages.	

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